

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application

Inventor(s): Jeffrey W. Carr
Appl. No.: 10/608,384
Confirm. No.: 7970
Filed: June 27, 2003
Title: Apparatus and Method for Reactive Atom
Plasma Processing for Material Deposition

PATENT APPLICATION

Art Unit: 1765
Examiner: Vinh, Lan
Docket No. RAPT-01000US4

Customer No. 23910

**AMENDMENT AND REPLY TO OFFICE
ACTION UNDER 37 C.F.R. § 1.116**

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

This Reply is in response to the Final Office Action dated January 5, 2007.

Amendments to the Claims are reflected in the listing of claims which begins on page 2
of this paper.

Remarks/Arguments begin on page 7 of this paper.